



Form 1449 (Modified)			Atty Docket No. <b>LAM1P182/P1183</b>	Application No.: <b>10/712,410</b>
Information Disclosure Statement By Applicant			Applicant: <b>Wagganer et al.</b>	
(Use Several Sheets if Necessary)			Filing Date <b>November 12, 2003</b>	Group <b>2818</b>

#### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
P D	A	5,658,425	08/19/97	Halman et al.	438	620	06/07/95
P D	B	6,080,680	06/27/00	Lee et al.	438	727	12/19/97
P D	C	6,090,304	07/18/00	Zhu et al.	216	79	08/28/97
P D	D	6,518,174B2	02/11/03	Annapragada et al.	438	637	12/22/00
	E						
	F						
	G						
	H						
	I						

#### Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
J								
K								
L								
M								
N								

#### Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication		
P D	O	Calvin T. Gabriel, et al., "Measuring and Minimizing Line Edge Roughness in BEOL Damascene Dielectric Patterning", 2003 AVS 4th Int'l. Conf. on Microelectronics and Interfaces, March 3-6, Santa Clara, CA, pages 204-207.		
	P			
	Q			
Examiner	PHUC T. DANG		Date Considered	1/29/05

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.